

III-V族半導体基板上 Epitaxial CIGS太陽電池の開発

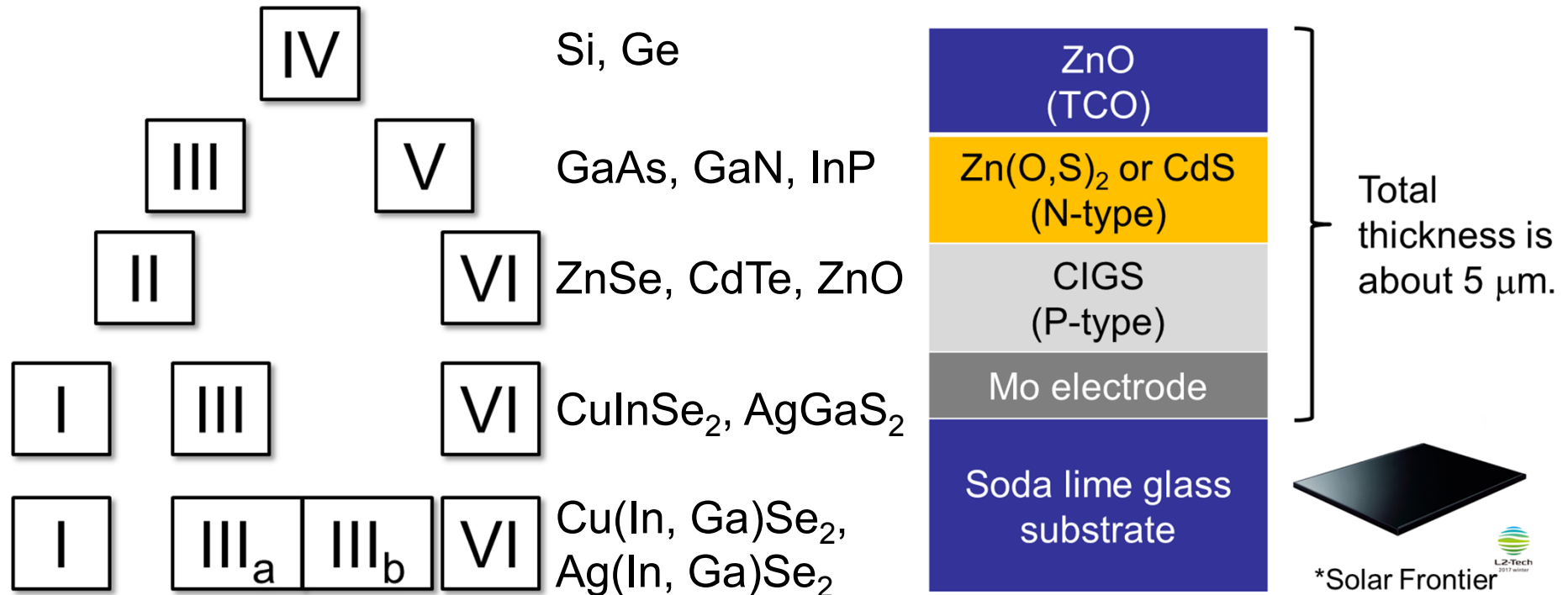
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化合物薄膜チーム、先進多接合デバイスチーム

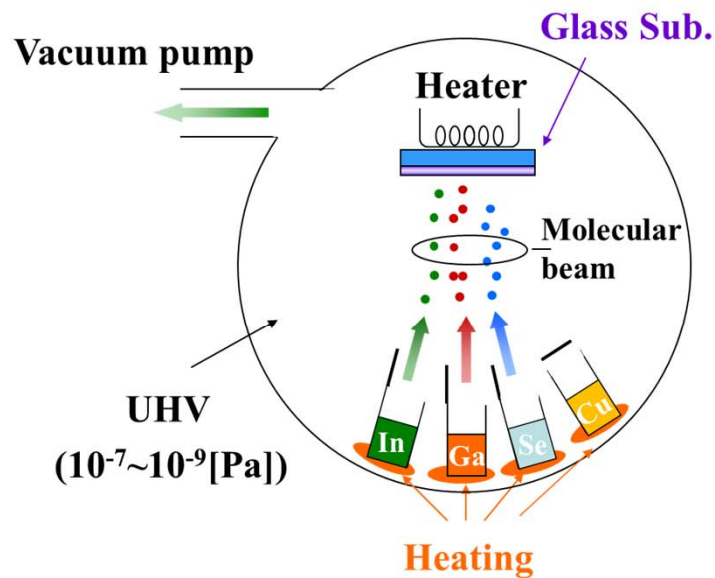
西永慈郎、石塚尚吾、菅谷武芳

Cu(In,Ga)Se₂ (CIGS)太陽電池

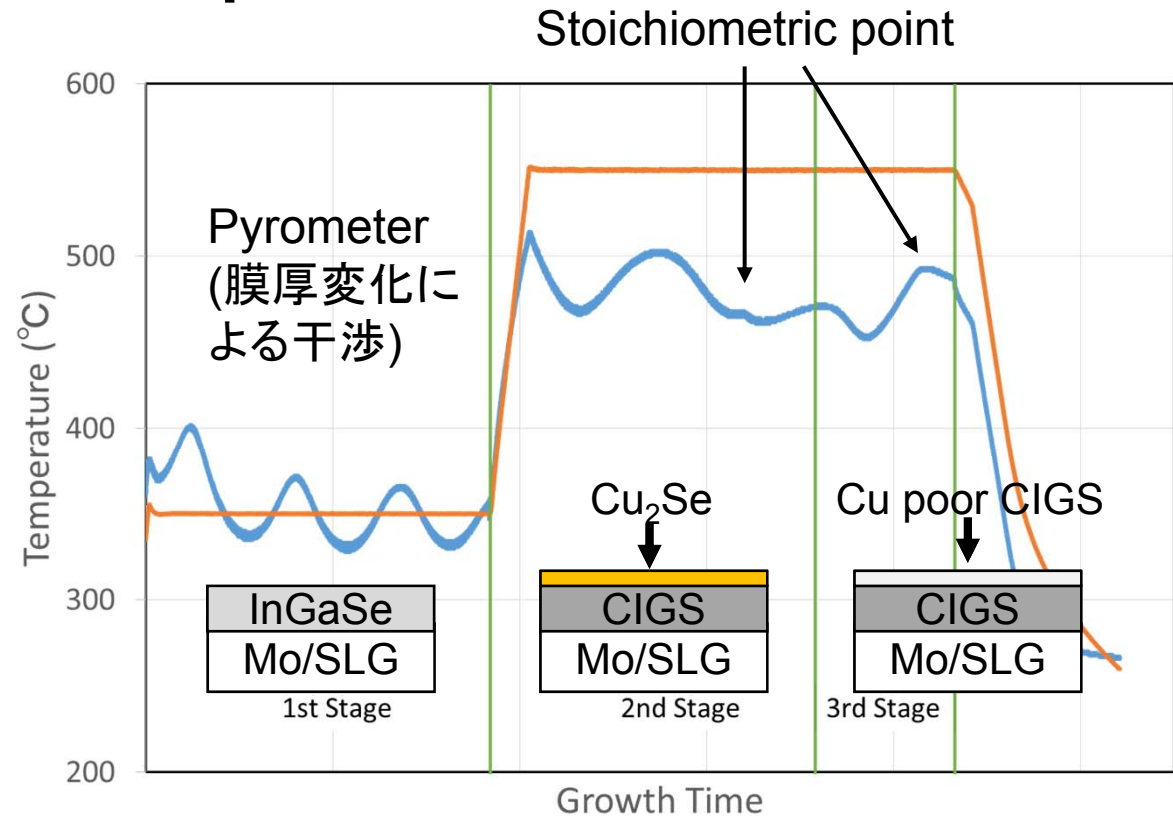


- I - III - VI₂族化合物半導体 (I - VI: イオン結合、III - VI: 共有結合)
- 欠陥による伝導型制御 (アクセプタ型欠陥(V_I), ドナー型欠陥(V_{VI}))
- ヘテロ構造によるデバイス応用 (ドーピングが困難、ヘテロ界面急峻性制御)
- 結晶粒界の不活化、Metastability (光励起、熱励起) の存在

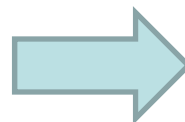
The 3-stage evaporation of CIGS



Molecular Beam Deposition

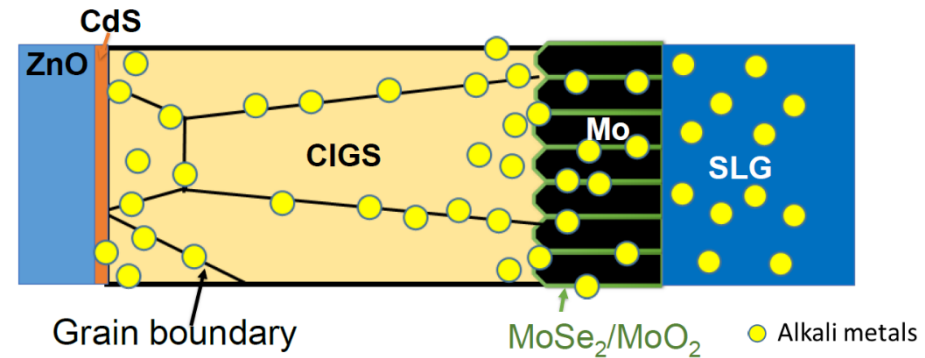
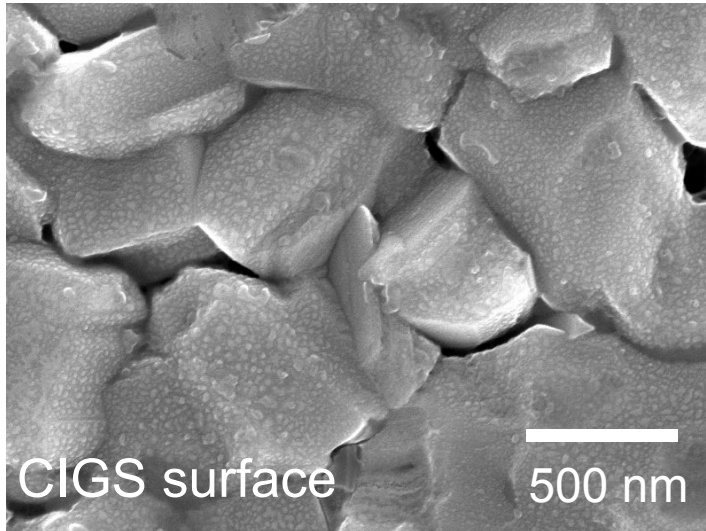


1st stage: In, Ga, Se
 2nd stage: Cu, Se
 3rd stage: In, Ga, Se

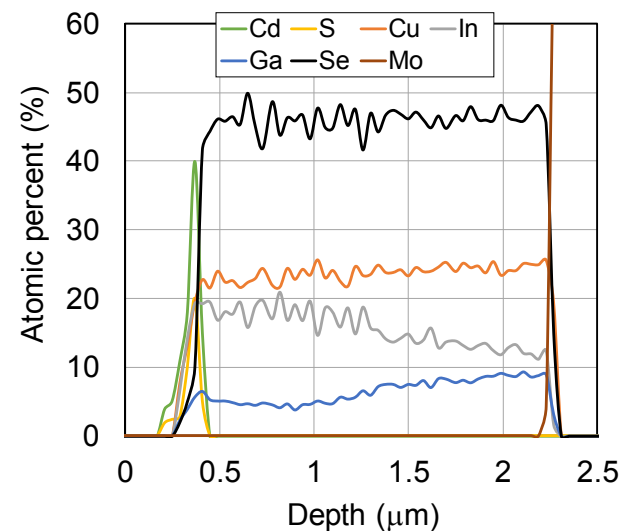
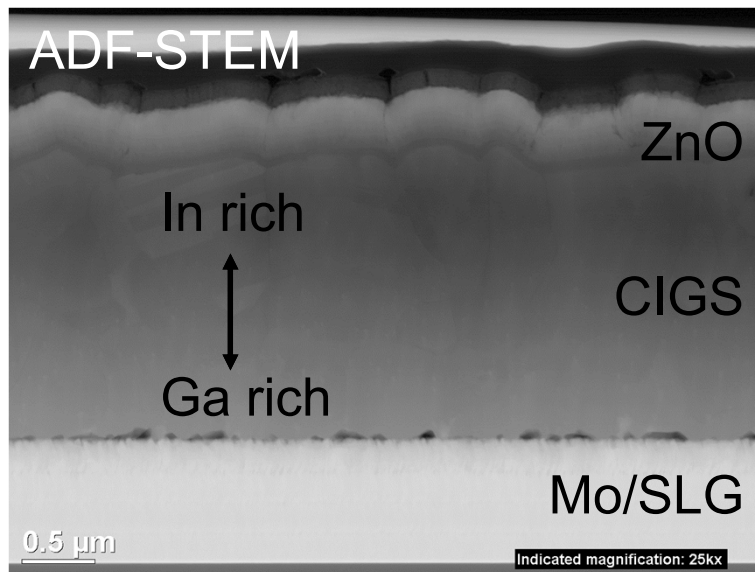


1st stage: $(\text{In,Ga})_2\text{Se}_3$
 2nd stage: $\text{Cu}(\text{In,Ga})\text{Se}_2 + \text{Cu}_2\text{Se}$
 3rd stage: $\text{Cu}(\text{In,Ga})\text{Se}_2 + \text{Cu}(\text{In,Ga})_3\text{Se}_5$

SEM, STEM images and EDX



Alkali metals passivate recombination centers.

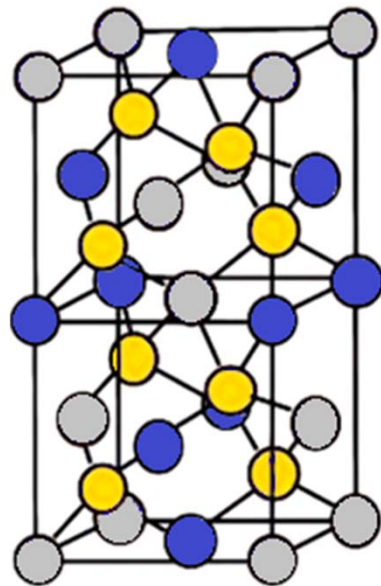


Cu₂Seへの溶解度の違いによって、In, Ga組成に勾配が発生する

変換効率23.4% (WR、ソーラーフロンティア社)を達成

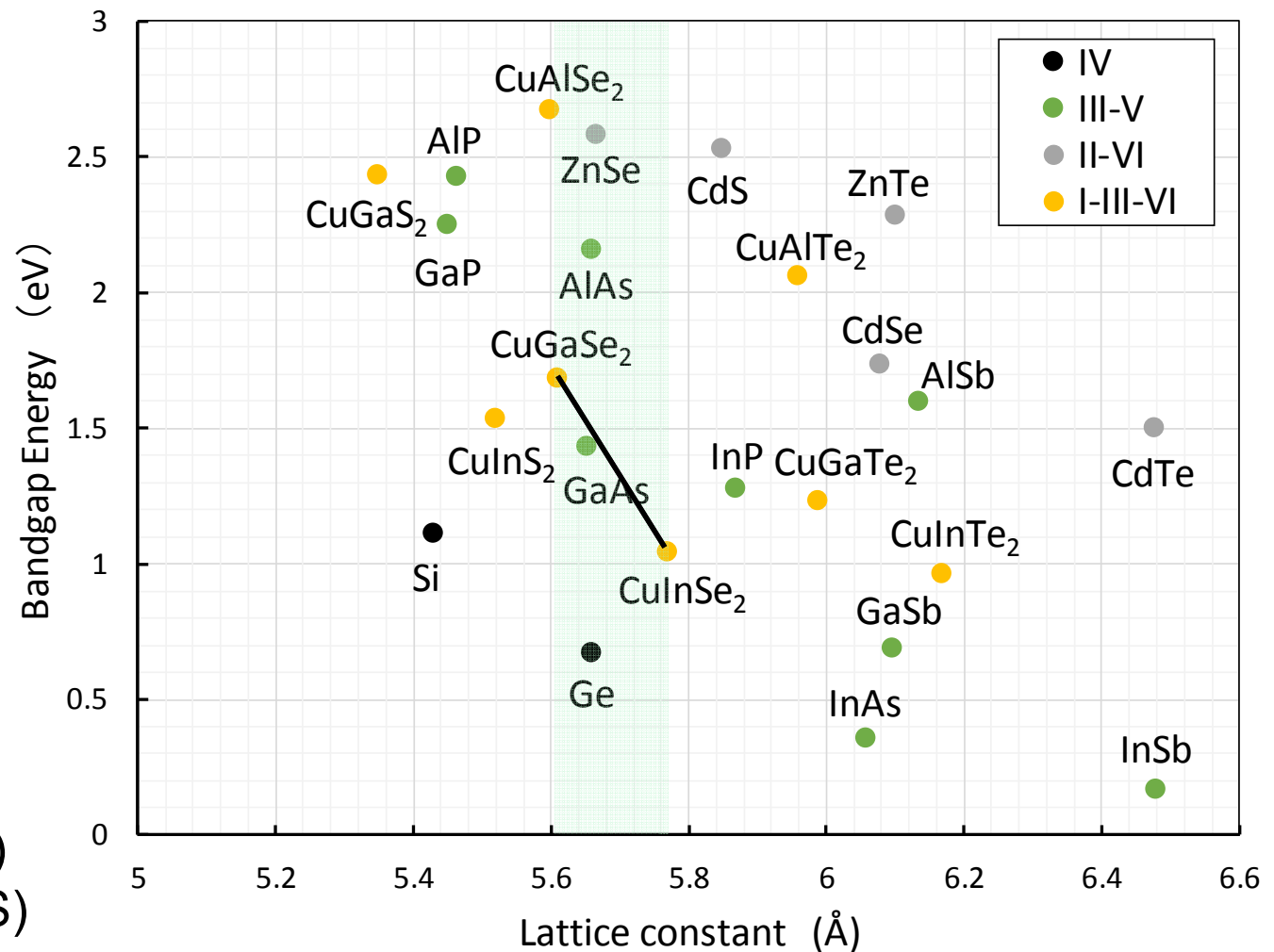
Lattice constant and Band-gap

Chalcopyrite structure



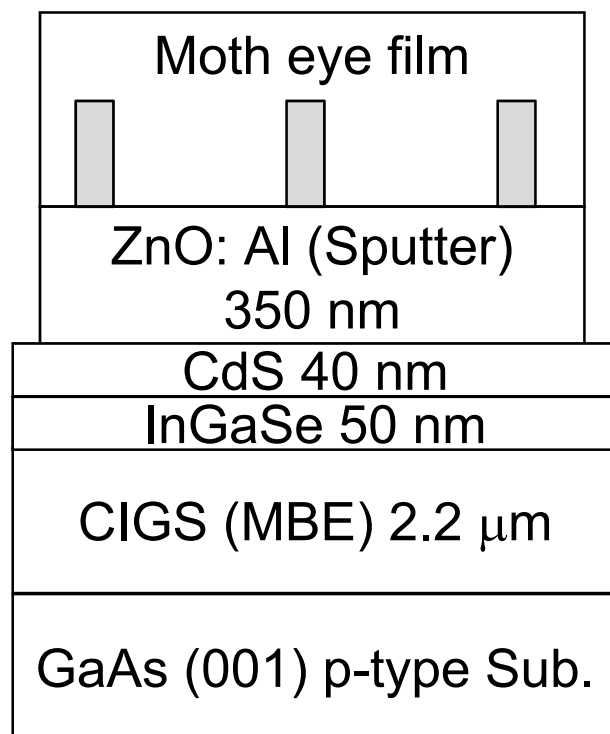
- Cu
- In, Ga
- Se

a axis: 5.76 Å (CIS)
c axis: 11.59 Å (CIS)



Epitaxial CIGS太陽電池の開発

CIGS solar cells

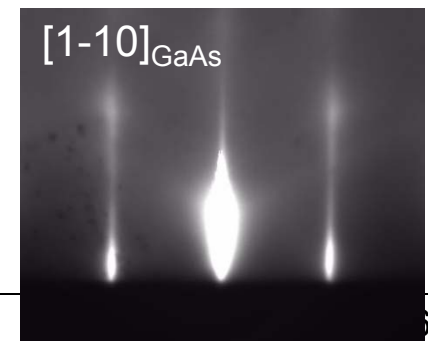
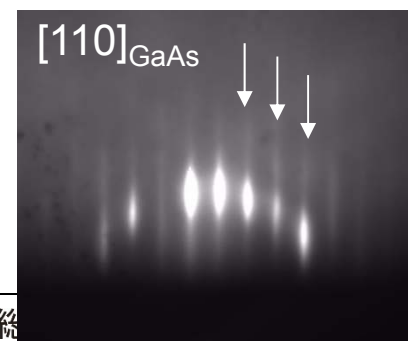
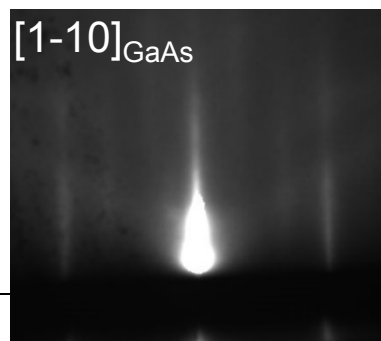
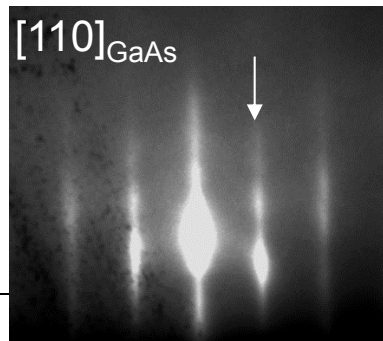
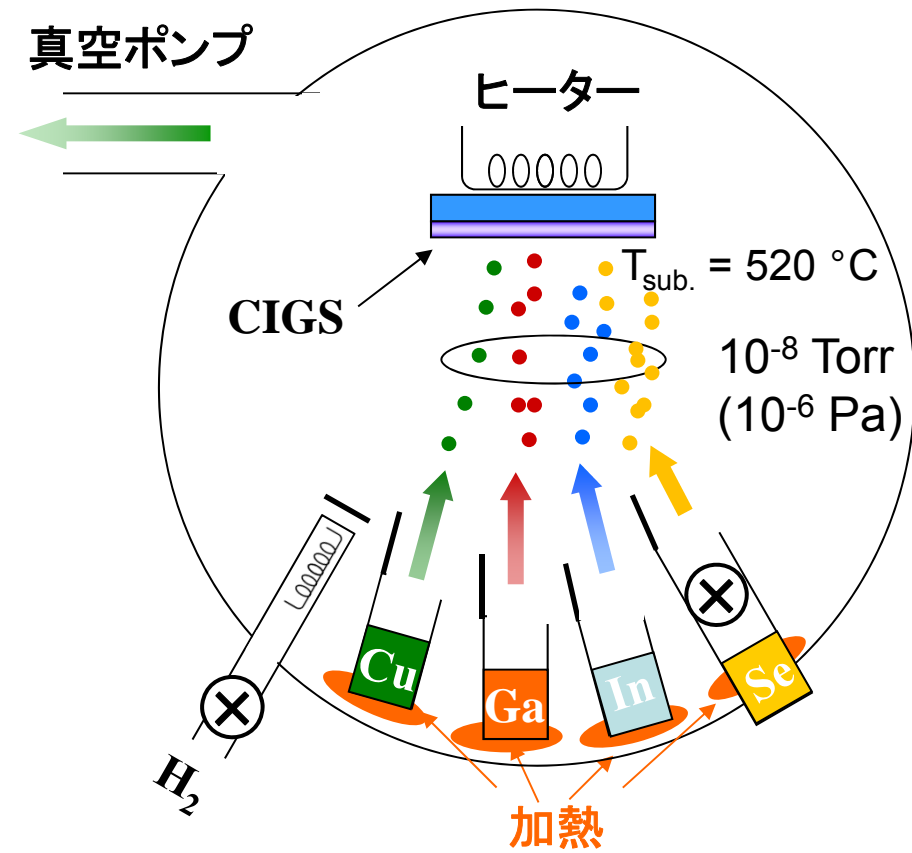
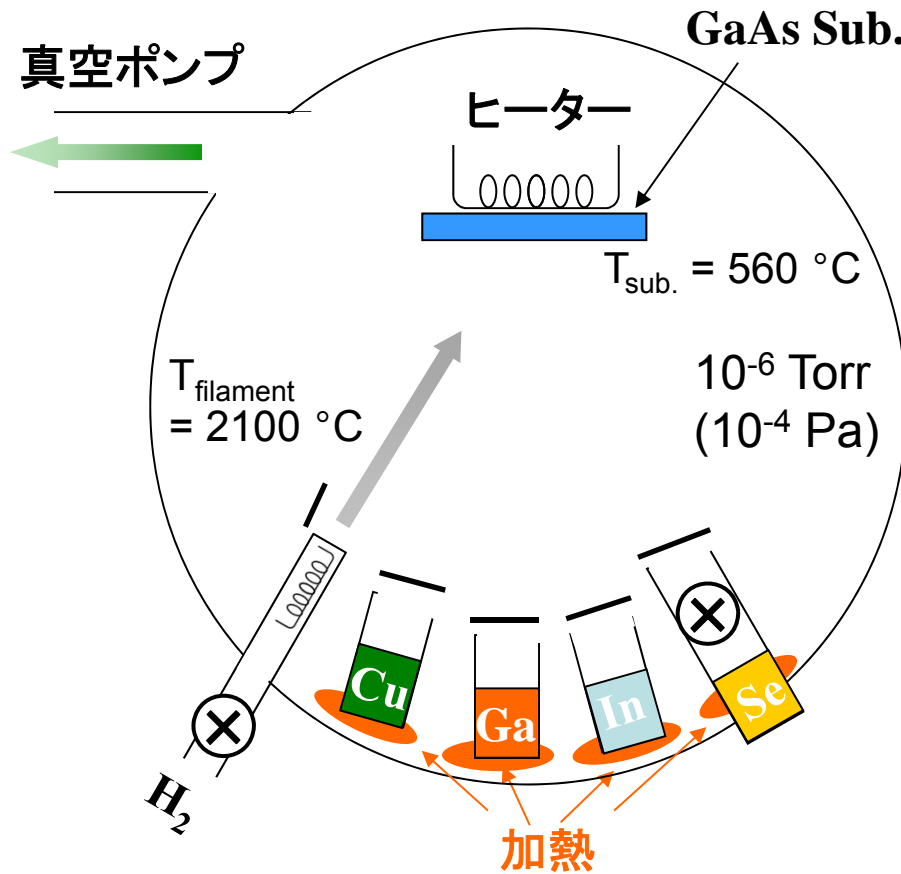


- Molecular beam epitaxy, $T_{\text{sub}}=520^{\circ}\text{C}$
(Same deposition: Cu, In, Ga, Se)
- $E_g=1.2$ eV (GGI:0.3), Cu濃度: 0.85–1.5
- アルカリ金属添加(Na doping, KF-PDT)
- CdS/AZO/Cr-Ag grid (Area: 0.2 cm²)

Measurements

- SEM, STEM
- *I*-*V* curves and *C*-*V* measurements

成膜法(基板表面処理、CIGS成膜)



Beam Equivalent Pressure (BEP)

$$\frac{J_i}{J_{Ga}} = \frac{P_i \eta_{Ga}}{P_{Ga} \eta_i} \sqrt{\frac{T_i M_{Ga}}{T_{Ga} M_i}}$$

$$\frac{\eta_i}{\eta_{N_2}} = \left(\frac{0.6 Z_i}{14} + 0.4 \right)$$

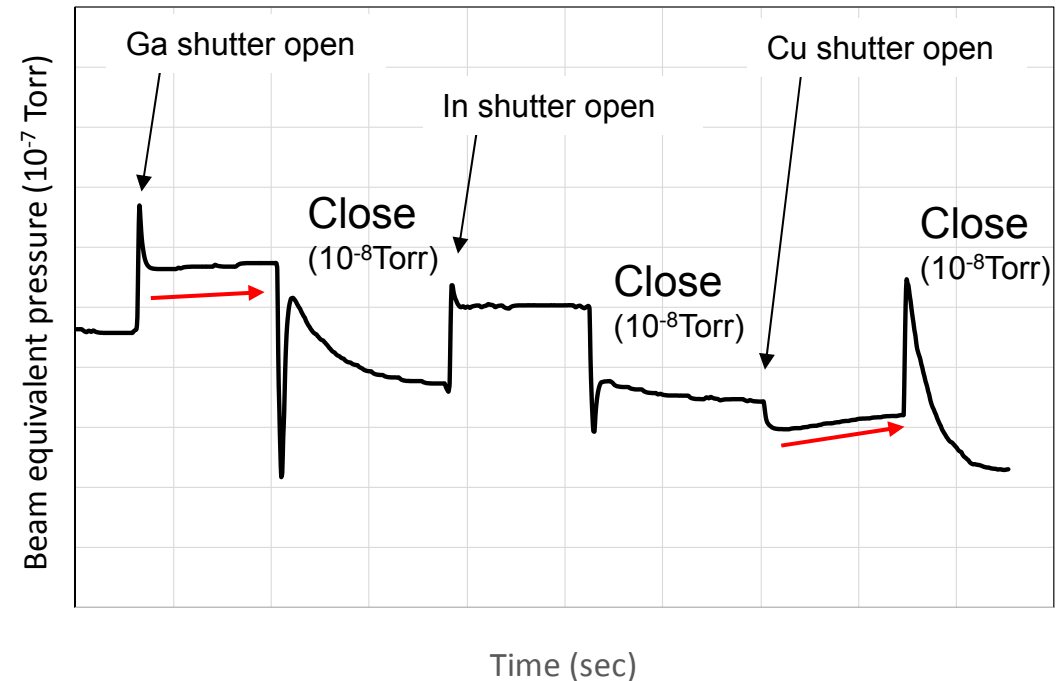
P_i : Beam equivalent pressure

M_i : Relative molecular mass

T_i : Absolute cell temperature

η_i : ionization efficiency

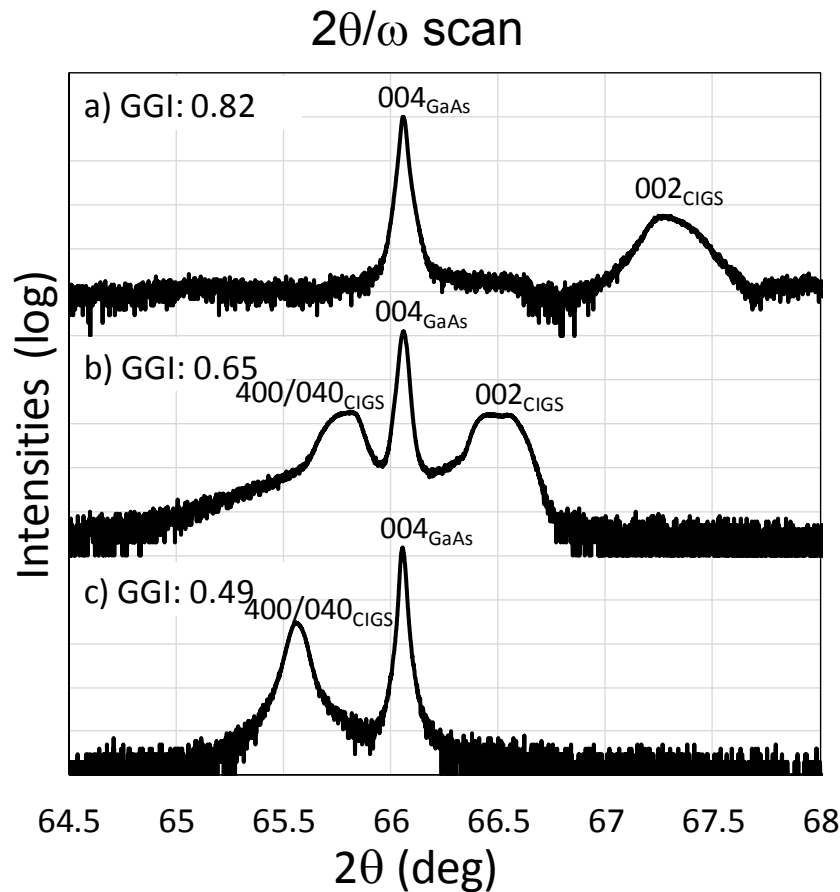
Z_i : number of electrons



$$BEP = BEP_{open} - BEP_{close} - BEP_{extra}$$

- $T_{Ga} = 945^\circ\text{C}$, $P_{Ga} = 3.22 \times 10^{-7}$ Torr
 - $T_{In} = 745^\circ\text{C}$, $P_{In} = 2.82 \times 10^{-7}$ Torr
 - $T_{Cu} = 1180^\circ\text{C}$, $P_{Cu} = 1.33 \times 10^{-7}$ Torr (CGI was measured by EPMA)
- } $GGI_{flux} = 0.7$
- } $CGI = 0.80$

Epitaxial Orientation of CIGS

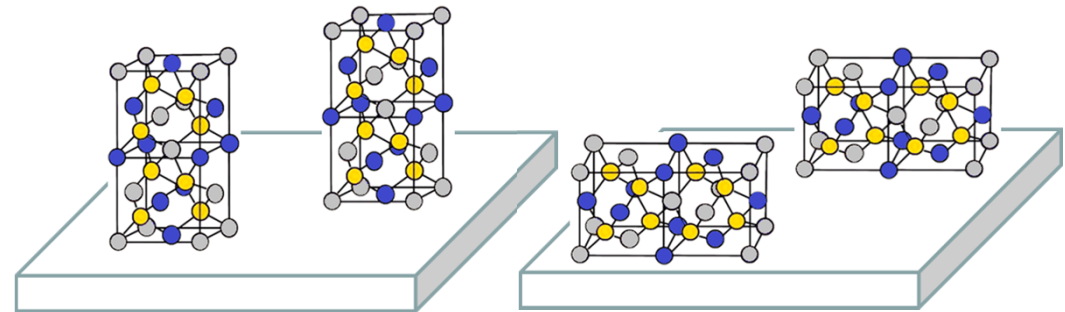


➔ GGI > 0.75 $[002]_{\text{CIGS}} // [001]_{\text{GaAs}}$
 GGI = 0.8: $a = b = 5.65 \text{ \AA}$, $c/2 = 5.57 \text{ \AA}$

➔ GGI < 0.65 $[100]_{\text{CIGS}} // [001]_{\text{GaAs}}$
 $[010]_{\text{CIGS}} // [001]_{\text{GaAs}}$
 GGI = 0.5: $a = b = 5.69 \text{ \AA}$, $c/2 = 5.65 \text{ \AA}$

GGI > 0.75

GGI < 0.65



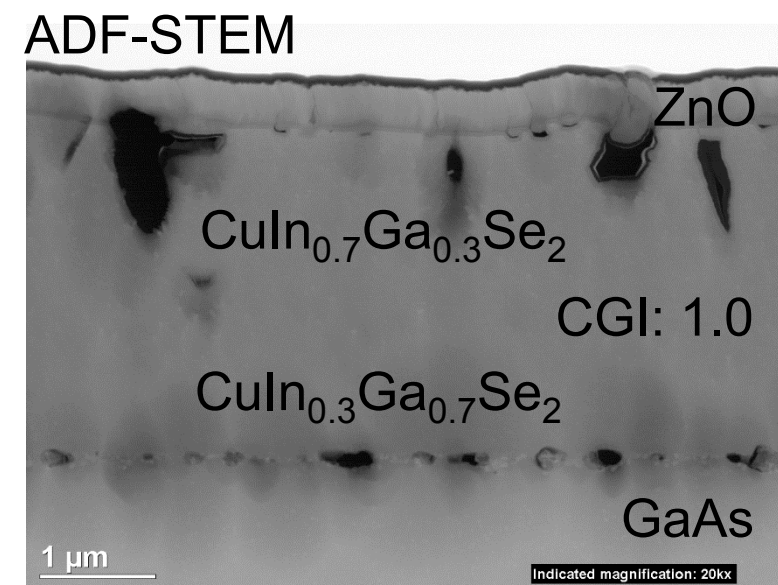
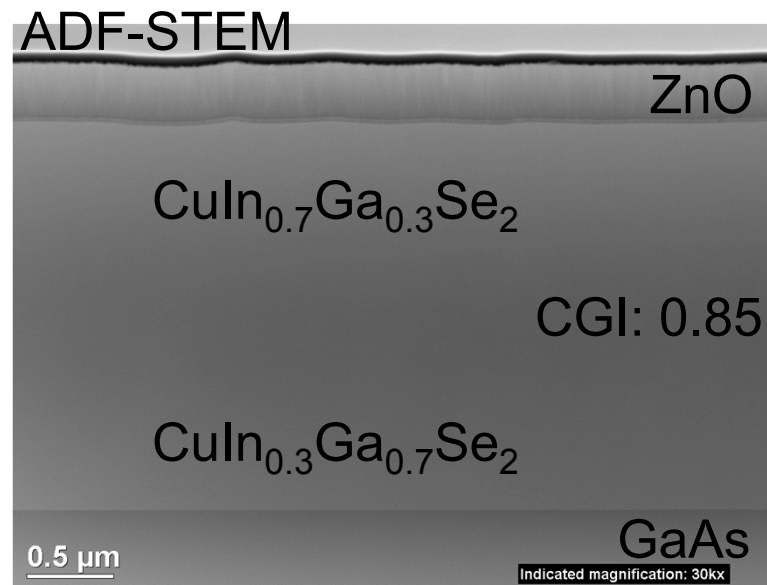
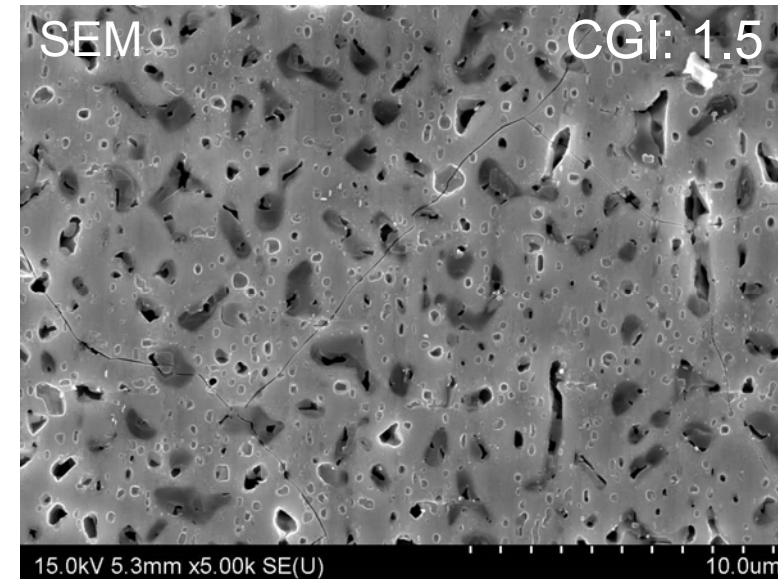
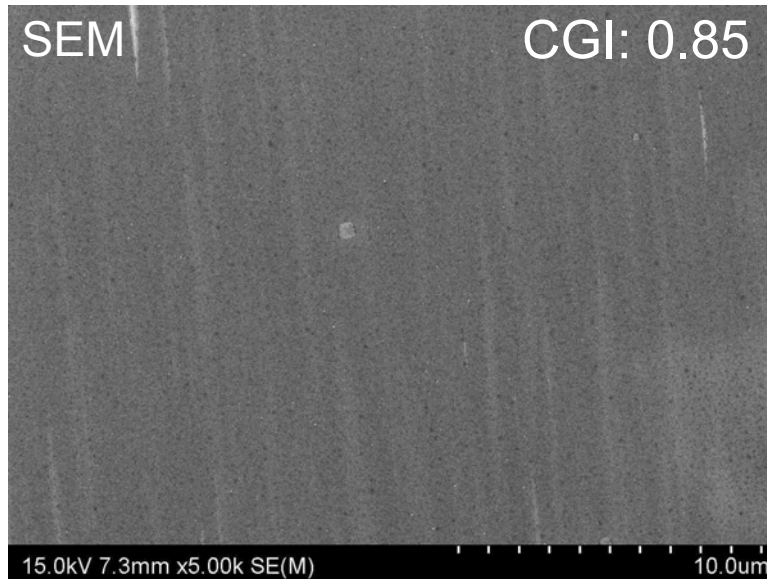
$[001]_{\text{GaAs}}$

$[010]_{\text{GaAs}}$

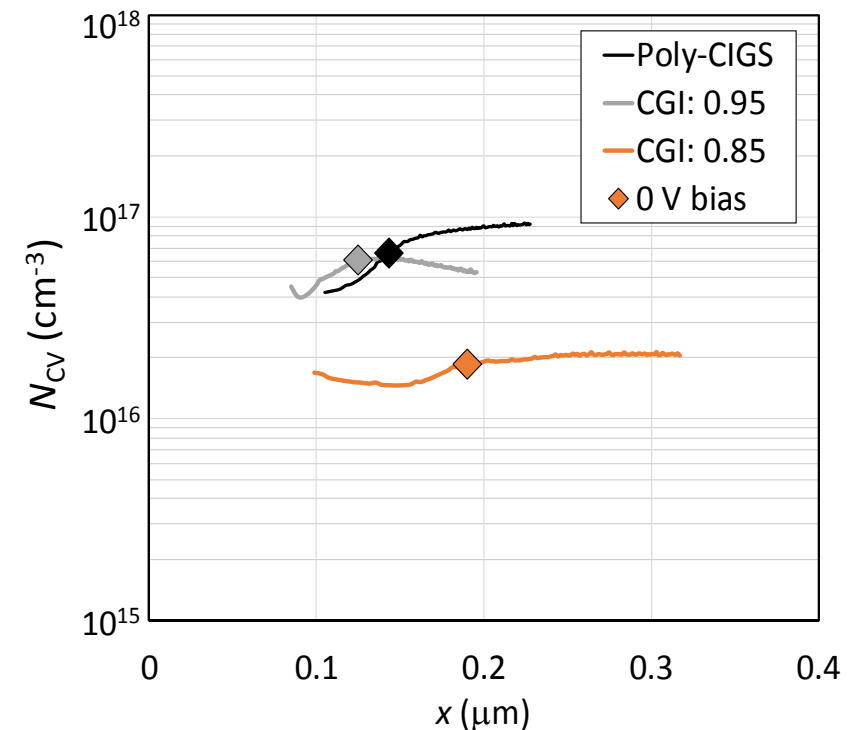
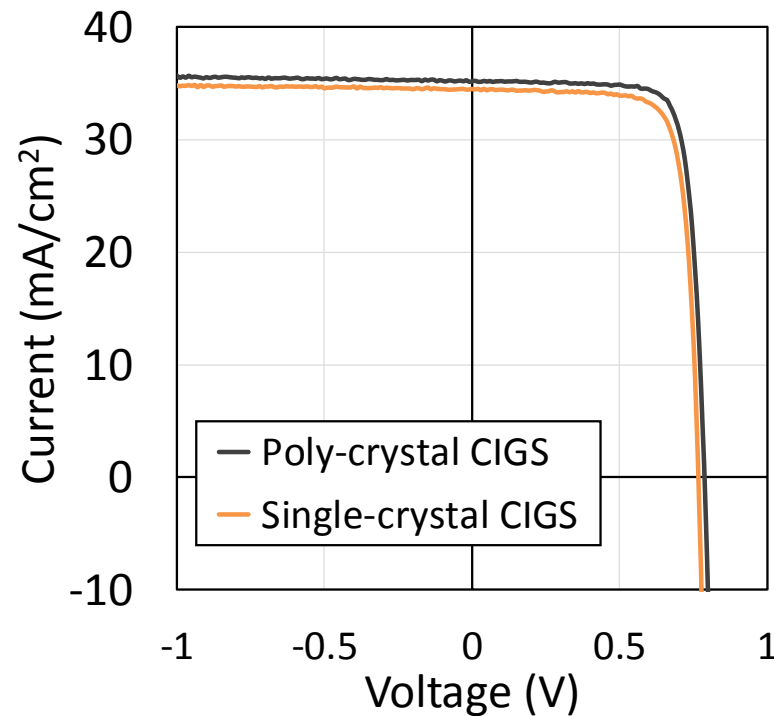
$[100]_{\text{GaAs}}$

GaAs (zinc blende)
 $a = b = c = 5.65 \text{ \AA}$

Cu poor CIGS or Cu rich CIGS

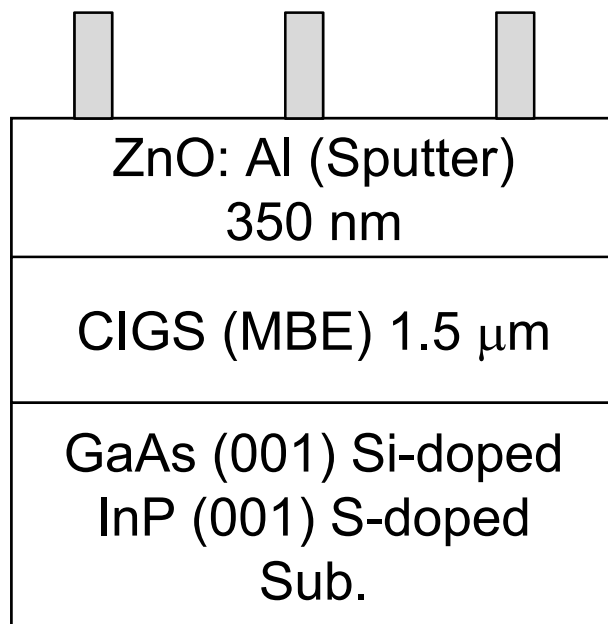


J-V curves and N_{CV} profiles



	Eff. (%)	V_{oc} (V)	J_{sc} (mA/cm ²)	FF	$R_{sh, dark}$ (Ωcm^2)	$R_{ser, dark}$ (Ωcm^2)	$N_{cv,0V}$ (cm ⁻³)	$J_{0,dark}$ (mA/cm ²)	n_{dark}
CGI: 0.85	20.9	0.767	34.5	0.789	1×10^5	0.08	2×10^{16}	4×10^{-9}	1.3
CGI: 0.95	16.7	0.737	33.2	0.683	26000	0.5	6×10^{16}	1×10^{-6}	1.7
Poly-CIGS	22.1	0.786	35.1	0.800	5700	0.34	7×10^{16}	3×10^{-9}	1.3

CIGS / n-type III-V 族化合物半導体



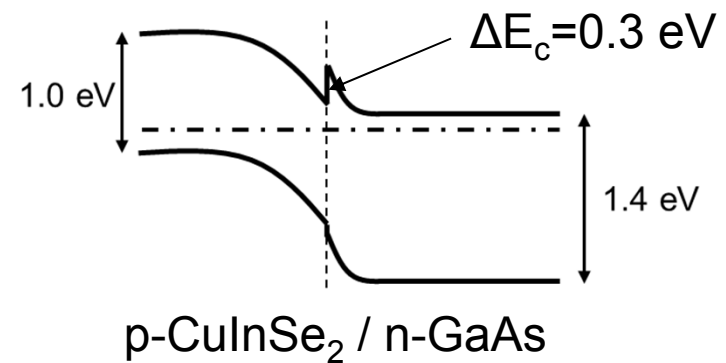
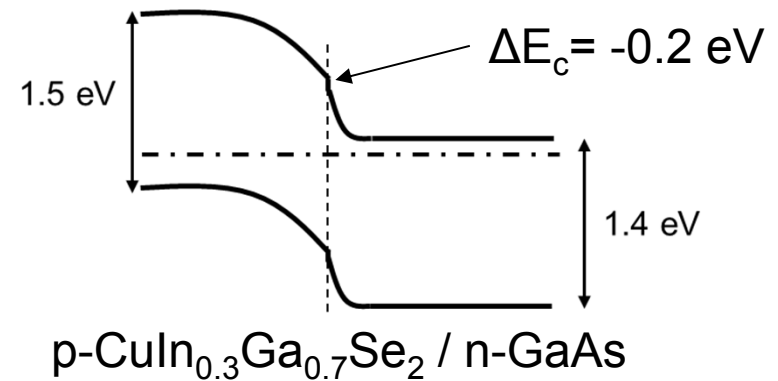
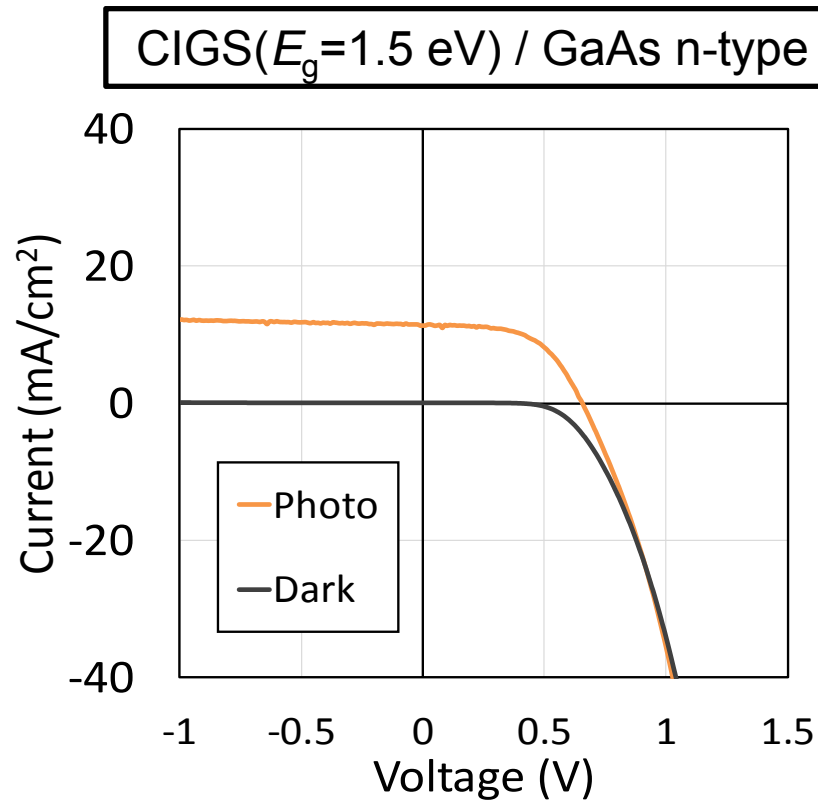
CIGS solar cells

- Molecular beam epitaxy
(Same deposition: Cu, In, Ga, Se)
- $E_g = 1.1, 1.5$ eV, Cu濃度: 0.85
- $T_{\text{Sub}} = 480 - 520^\circ\text{C}$
- NaF doping
- AZO/Cr-Ag grid (Area: 0.25 cm²)

Measurements

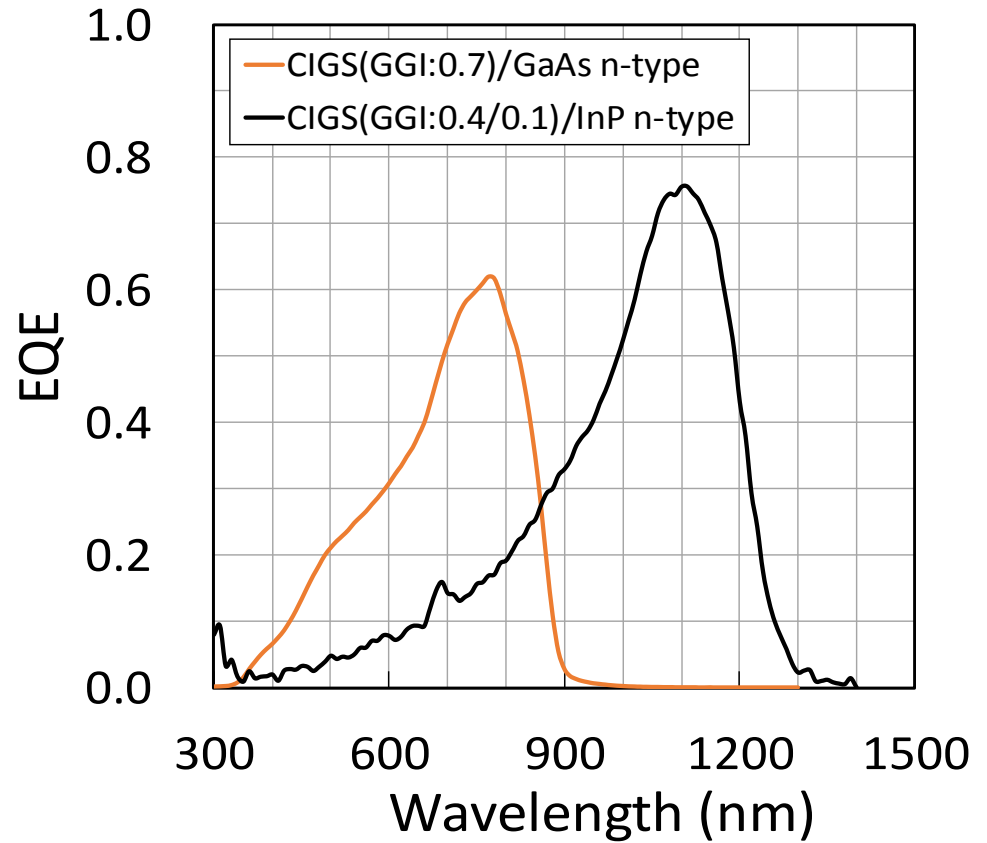
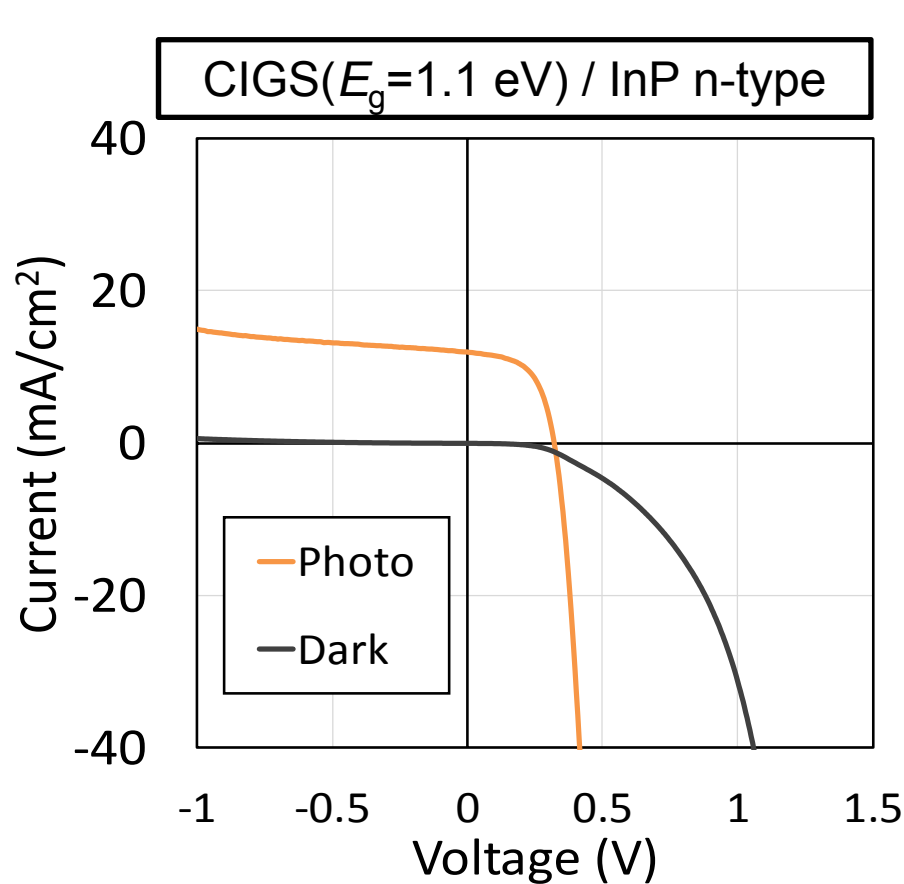
- *I-V* curves and *EQE*

CIGS / GaAs n-type

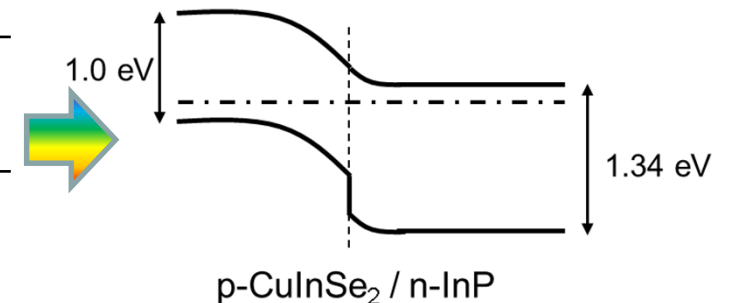


	Eff. (%)	V_{oc} (V)	J_{sc} (mA/cm ²)	FF
GGI: 0.7	4.2	0.655	11.3	0.57
GGI: 0.4/0.1	0.0	0.0	0.0	-

低Ga濃度CIGS / InP n-type



	Eff. (%)	V_{oc} (V)	J_{sc} (mA/cm ²)	FF
CIGS(GGI:0.4/0.1) / InP n-type	2.2	0.322	12.0	0.56



まとめ

➡ I - III - VI₂ 族化合物半導体の組成制御

- 相分離を利用した気相・固相成長、組成制御
- CIGS系の特徴は、薄膜太陽電池応用に最適

➡ III - V 族化合物半導体 / CIGSへテロ構造

- 格子定数、組成、界面反応の制御が重要
- 電子親和力でバンド構造を説明可能

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